

US005312778A

United States Patent [19]

Collins et al.

[11] Patent Number:

5,312,778

45] Date of Patent:

May 17, 1994

[54] METHOD FOR PLASMA PROCESSING USING MAGNETICALLY ENHANCED PLASMA CHEMICAL VAPOR DEPOSITION

[75] Inventors: Kenneth S. Collins, San Jose;

Chan-Lon Yang, Los Gatos; John M.

White, Hayward, all of Calif.

[73] Assignee: Applied Materials, Inc., Santa Clara, Calif.

740 440

[21] Appl. No.: 618,142

[22] Filed: Nov. 23, 1990

Related U.S. Application Data

[63] Continuation-in-part of Ser. No. 559,947, Jul. 31, 1990, abandoned, and a continuation-in-part of Ser. No. 560,530, Jul. 31, 1990, abandoned, each is a continuation-in-part of Ser. No. 416,750, Oct. 3, 1989, abandoned.

[51]	Int. Cl.5	H01L 21/00; H01L 21/02;
		H01L 21/302; H01L 21/463
real	TIC O	425 /33E, 427 /330.

[52] U.S. Cl. 437/228; 437/228; 427/571

[56]

References Cited

U.S. PATENT DOCUMENTS

3,860,507	1/1975	Vossen, Jr	437/225
4,369,205	1/1983	Winterling et al	427/571
4,521,286	6/1985	Horwitz	437/225
4,526,643	7/1985	Okano et al	156/345
4,572,759	2/1986	Benzing	156/345
4,623,417	11/1986	Spencer et al	156/345
4,632,719	12/1986	Chow et al	156/345
4,673,589	6/1987	Standley	427/41
4,761,219	8/1988	Sasaki et al	204/298
4,776,918	10/1988	Otsubo et al	156/345
4,808,258	2/1989	Otsubo et al	156/643
4,842,683	6/1989	Cheng et al	156/345
4,874,494	10/1989	Ohmi 20	4/192.12
4,891,095	1/1990	Ishida et al	156/643
5,011,705	4/1991	Tanaka	427/571

FOREIGN PATENT DOCUMENTS

0272142	6/1988	European Pat. Off	
0326405	8/1989	European Pat. Off	
0343017	11/1989	European Pat. Off	
0396919	11/1990	European Pat. Off	
0421430	4/1991	European Pat. Off	
0208125	12/1982	Japan	. 427/571
0176224	9/1985	Japan	. 427/571
0026597	2/1986	Japan	. 427/571
0185915	7/1989	Japan	. 427/571
0237117	9/1990	Japan	. 427/571
0146661	6/1991	Japan	. 427/571

OTHER PUBLICATIONS

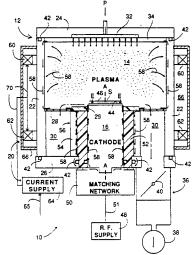
Ohmi, From Alchemy To Science: Technological Challenges Sep. 1, 1989.

Primary Examiner—Brian E. Hearn
Assistant Examiner—B. Everhart
Attorney, Agent, or Firm—Noel F. Heal
.

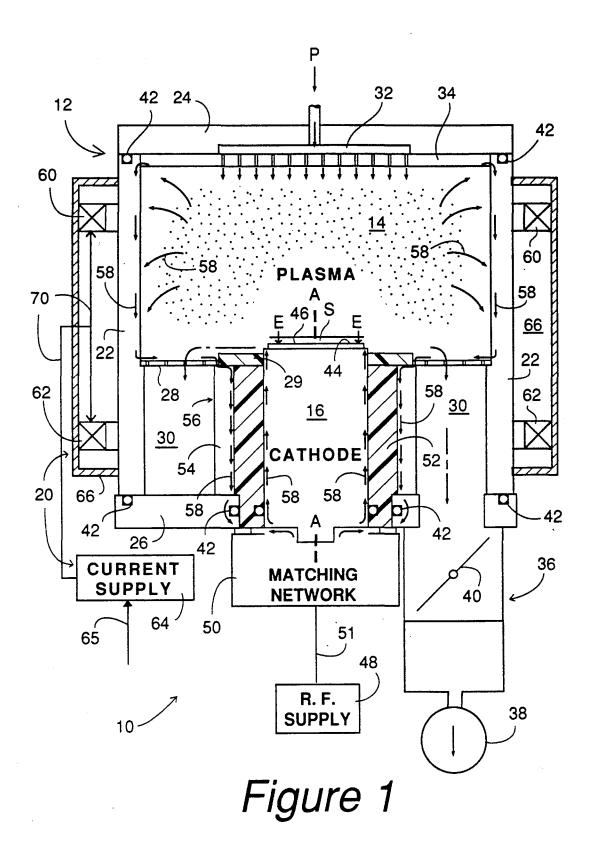
[57] ABSTRACT

A method for plasma processing characterized by the steps of disposing a wafer proximate to a cathode within a process chamber, releasing a gas into the chamber, applying R.F. power in the VHF/UHF frequency range to the cathode to form a plasma within the chamber, developing a magnetic field within the chamber having flux lines substantially perpendicular to the surface of the wafer, and varying the strength of the magnetic field until a desired cathode sheath voltage is attained. The apparatus includes a chamber, a wafer-supporting cathode disposed within the chamber, a mechanism for introducing gas into the chamber, an R.F. power source coupled to the cathode operating in the frequency from about 50-800 megahertz, an electromagnetic coil disposed around the chamber adapted to develop a magnetic field within the chamber which is substantially perpendicular to the wafer and a variable output power supply coupled to the coil to vary the magnetic field strength and therefore the cathode sheath voltage within the chamber.

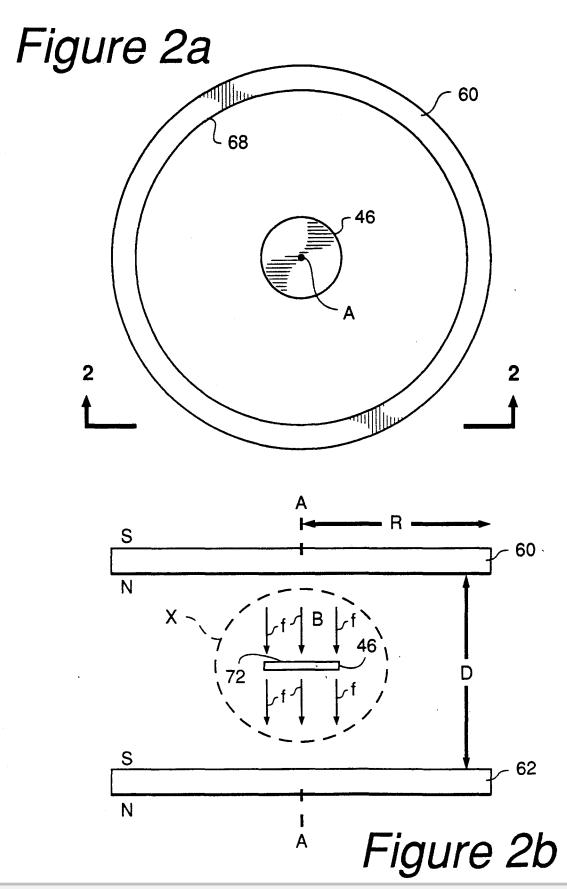
15 Claims, 5 Drawing Sheets



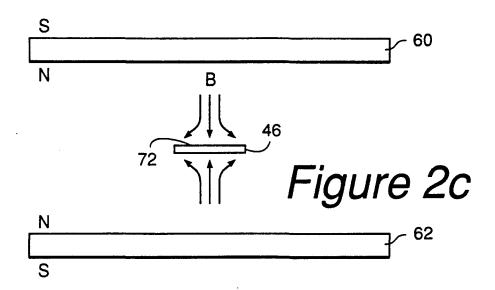


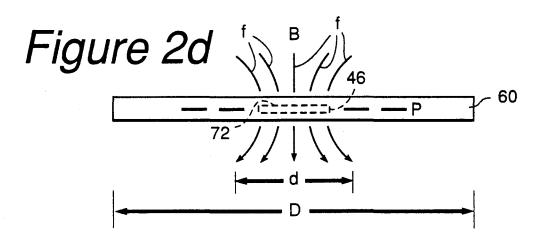


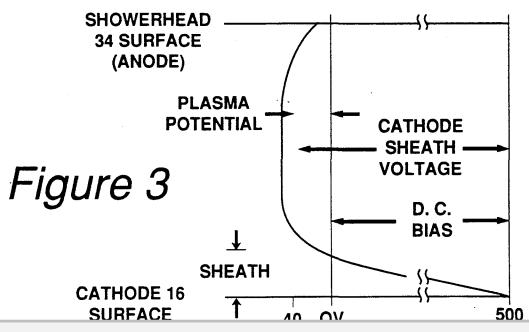




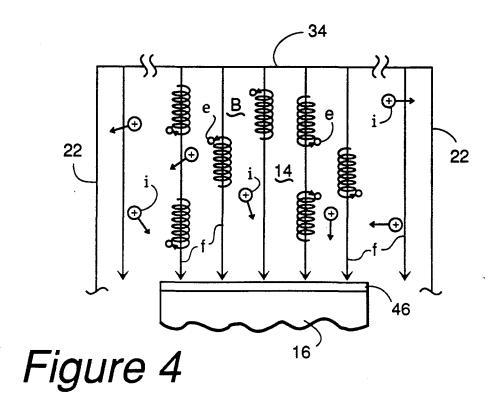


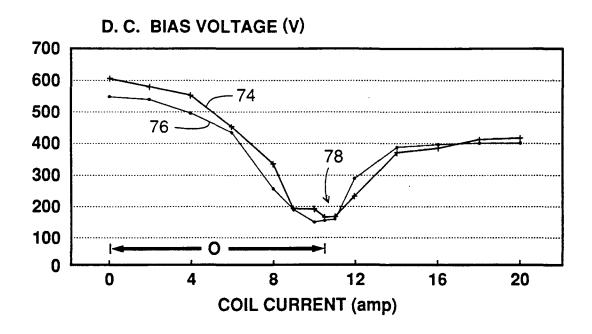
















DOCKET A L A R M

Explore Litigation Insights



Docket Alarm provides insights to develop a more informed litigation strategy and the peace of mind of knowing you're on top of things.

Real-Time Litigation Alerts



Keep your litigation team up-to-date with **real-time** alerts and advanced team management tools built for the enterprise, all while greatly reducing PACER spend.

Our comprehensive service means we can handle Federal, State, and Administrative courts across the country.

Advanced Docket Research



With over 230 million records, Docket Alarm's cloud-native docket research platform finds what other services can't. Coverage includes Federal, State, plus PTAB, TTAB, ITC and NLRB decisions, all in one place.

Identify arguments that have been successful in the past with full text, pinpoint searching. Link to case law cited within any court document via Fastcase.

Analytics At Your Fingertips



Learn what happened the last time a particular judge, opposing counsel or company faced cases similar to yours.

Advanced out-of-the-box PTAB and TTAB analytics are always at your fingertips.

API

Docket Alarm offers a powerful API (application programming interface) to developers that want to integrate case filings into their apps.

LAW FIRMS

Build custom dashboards for your attorneys and clients with live data direct from the court.

Automate many repetitive legal tasks like conflict checks, document management, and marketing.

FINANCIAL INSTITUTIONS

Litigation and bankruptcy checks for companies and debtors.

E-DISCOVERY AND LEGAL VENDORS

Sync your system to PACER to automate legal marketing.

